

# The Restoring Casimir Force between Doped Silicon Slab and Metamaterials

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**Abstract**—Casimir effect is an observable macroscopic quantum effect. It has significant influence on micro-machine and nano-machine. Based on a generalization of the Lifshitz theory, we calculate Casimir force between the doped silicon slab and metamaterials. From simulating, we can see that the magnitude and the direction of the Casimir force can be changed by varying doping level, the thickness of doped silicon slab, and filling factor of metamaterials. Thus the force can be controlled by tuning these parameters. It can be restoring force in a certain range of distance, which can provide a method to deal with the stability problem, and bring much meaningful results from the practical views.

**Key words:** Repulsive and Restoring Casimir Force; Doped Silicon; Metamaterials

## I. INTRODUCTION

Casimir effect results from the change of zero-point energy due to the existence of the boundaries and may be observed as a vacuum force. In 1948, this effect, the attractive interaction of a pair of neutral perfectly conducting parallel plates placed in the vacuum, was first proposed and theoretically derived by Casimir<sup>[1]</sup>. In recent years, the Casimir effect has attracted considerable attention. Especially, with the development of nanotechnology, Casimir force has a significant impact on the micro-electromechanical systems (MEMS) and nano-electromechanical (NEMS)<sup>[2-4]</sup>. It can be applied to dynamic devices, but also can be lead to stiction problem in MEMS and NEMS. Therefore, Casimir force has become a current research hot spot.

Boyer pointed out a repulsive Casimir force may rise between a perfect conductor plate and a material plate with infinite permeability<sup>[5]</sup>. But the material in the nature usually has not strong magnetic response in near-infrared and optical spectrum. However, with the development of artificial metamaterials, strong magnetic response material can be obtained, which provides the conditions to get a repulsive Casimir force. Various calculation techniques have been developed, and Lifshitz theory coincides well with the experimental results<sup>[6,7]</sup>. Therefore, based on Lifshitz theory, we calculate the Casimir forces between doped silicon slab and metamaterials in vacuum, and study the changes of Casimir forces due to the changes of the doping level, the thickness of slab, and the filling factor of metamaterials.

## II. THE INTERACTION BETWEEN DOPED SILICON SLAB AND METAMATERIALS

Let us consider the configuration with an infinite doped silicon slab and thick metamaterials plate separated by a distance  $d$ , in the vacuum. The thickness of doped silicon slab is  $D$ . Based on Lifshitz theory, the resulting Casimir force per unit area  $A$  is eventually expressed as<sup>[8,9]</sup>

$$\frac{F(d)}{A} = \frac{\hbar}{2\pi^2} \int_0^\infty d\xi \int_0^\infty k_\parallel dk_\parallel \times \sum_\alpha \frac{r_\alpha^{(1)} r_\alpha^{(2)}}{e^{2k_\alpha d} - r_\alpha^{(1)} r_\alpha^{(2)}}, \quad (1)$$

where  $k_\parallel$  is the component of the wave vector parallel to the slab surface, and  $r_\alpha$  ( $\alpha = \text{TE, TM}$ ) is the reflection coefficient for TE- or TM-polarized waves. In  $r_\alpha^{(j)}$ , superscripts  $j=1, 2$  stands for the doped silicon slab and metamaterials, respectively.  $k_\alpha = \sqrt{k_\parallel^2 + \xi^2/c^2}$ ,  $c$  is the speed of light in the vacuum.

The reflection coefficients for  $p$ -doped silicon are gave as

$$r_{\text{TM}}^{(1)} = \left( \varepsilon_1 k_0 - \sqrt{k_\parallel^2 + \varepsilon_1 \xi^2/c^2} \right) / \left( \varepsilon_1 k_0 + \sqrt{k_\parallel^2 + \varepsilon_1 \xi^2/c^2} \right), \quad (2a)$$

$$r_{\text{TE}}^{(1)} = \left( k_0 - \sqrt{k_\parallel^2 + \varepsilon_1 \xi^2/c^2} \right) / \left( k_0 + \sqrt{k_\parallel^2 + \varepsilon_1 \xi^2/c^2} \right). \quad (2b)$$

Here we characterize the electric response of doped silicon as<sup>[10]</sup>

$$\varepsilon_1(i\xi) = \varepsilon_{si}(i\xi) + \frac{\omega_p^2}{\xi^2 + \gamma\xi}, \quad (3)$$

$$\varepsilon_{si}(i\xi) = \varepsilon_\infty + \frac{(\varepsilon_0 - \varepsilon_\infty)\omega_{si}^2}{\xi^2 + \omega_{si}^2}, \quad (4)$$

$$\omega_p = \sqrt{\frac{Ne^2}{\varepsilon_0 m^*}} = \frac{2\pi c}{\lambda_p}, \gamma = \frac{Ne^2 \rho}{m^*}, \quad (5)$$

where  $\varepsilon_{si}$  is the dielectric function of intrinsic silicon, and  $\varepsilon_\infty = 1.035$ ,  $\varepsilon_0 = 11.87$ ,  $\omega_{si} = 6.6 \times 10^{15} \text{ rad/s}$ .  $m^* = 0.34m_e$  is the effective mass of the charge carrier in the silicon crystal, and  $m_e$  is the electron mass.  $\rho$  is the resistivity of silicon, and  $N$  corresponds to the doping level. The different values of the plasma frequency  $\omega_p$  and the relaxation ratio  $\gamma$  for various densities are given in Table 1<sup>[10]</sup>.

Considering the role of the thickness  $D$  of the doped silicon slab on the Casimir interaction, the reflection coefficients  $r_{\text{TM}}^{(1)}$  and  $r_{\text{TE}}^{(1)}$  in Eq. (2a) and Eq. (2b) become<sup>[9,11]</sup>

Table 1 the plasma frequency  $\omega_p$  and relaxation ratio  $\gamma$  for various doping levels

$N/\text{cm}^{-3}$	$\omega_p / \times 10^{12} \text{ rad / s}$	$\gamma / \times 10^{13} \text{ s}^{-1}$	$\rho / \Omega\text{cm}$
$1.1 \times 10^{15}$	3.1899	1.18482	13
$1.3 \times 10^{18}$	110.1275	3.75193	$3.5 \times 10^{-2}$
$1.4 \times 10^{19}$	361.522	7.86842	$6.8 \times 10^{-3}$
$1.0 \times 10^{20}$	966.084	9.917551	$1.2 \times 10^{-3}$

$$r_{TM}^{(1)} \rightarrow r_{TM}^{(1)} \frac{1 - e^{-2\sqrt{k_{\parallel}^2 + \epsilon_1 \xi^2 / c^2} D}}{1 - r_{TM}^{(1)2} e^{-2\sqrt{k_{\parallel}^2 + \epsilon_1 \xi^2 / c^2} D}}, \quad (6a)$$

$$r_{TE}^{(1)} \rightarrow r_{TE}^{(1)} \frac{1 - e^{-2\sqrt{k_{\parallel}^2 + \epsilon_1 \xi^2 / c^2} D}}{1 - r_{TE}^{(1)2} e^{-2\sqrt{k_{\parallel}^2 + \epsilon_1 \xi^2 / c^2} D}}. \quad (6b)$$

The reflection coefficient for metamaterials are gave as [8]

$$r_{TM}^{(2)} = \left( \epsilon_2 k_0 - \sqrt{k_{\parallel}^2 + \epsilon_2 \xi^2 / c^2} \right) / \left( \epsilon_2 k_0 + \sqrt{k_{\parallel}^2 + \epsilon_2 \xi^2 / c^2} \right), \quad (7a)$$

$$r_{TE}^{(2)} = \left( \mu_2 k_0 - \sqrt{k_{\parallel}^2 + \mu_2 \xi^2 / c^2} \right) / \left( \mu_2 k_0 + \sqrt{k_{\parallel}^2 + \mu_2 \xi^2 / c^2} \right). \quad (7b)$$

For metamaterials with partly metallic, we assume that the dielectric function has a Drude background response in addition to the resonant part. Here the optical parameters of metallic-based metamaterials are characterized by

$$\epsilon_2(i\xi) = 1 + f \frac{\Omega_D}{\xi^2 + \gamma_D \xi} + (1-f) \frac{\Omega_e}{\xi^2 + \omega_e^2 + \gamma_e \xi}, \quad (8a)$$

$$\mu(i\xi) = 1 + \frac{\Omega_m^2}{\omega_m^2 + \xi^2 + \gamma_m \xi}, \quad (8b)$$

where  $\Omega_e$  and  $\Omega_m$  are plasma frequency,  $\omega_e$  ( $\omega_m$ ) is the electric (magnetic) resonance frequency, and  $\gamma_e$  ( $\gamma_m$ ) is the metamaterials electric (magnetic) dissipation parameter.  $\Omega_D$  and  $\gamma_D$  are the Drude parameters of this metallic structure.  $f$  is the filling factor that accounts for the fraction of structure contained in the metamaterials. We choose  $\omega_0 = 10^{14} \text{ rad / s}$ . For metamaterials with silver material, the corresponding parameters are:  $\Omega_e = 0.04\Omega_D$ ,  $\Omega_m = 0.1\Omega_D$ ,  $\omega_e = \omega_m = 0.1\Omega_D$ ,  $\gamma_D = 0.002\Omega_D$ ,  $\gamma_e = \gamma_m = 0.005\Omega_D$ ,  $\Omega_D = 137.036\omega_0$ .

### III. THE SIMULATION AND THE RESULT ANALYSIS

We first consider the relative Casimir force  $10^3 Fd^3 / A\hbar c K_0$  between metamaterials and doped silicon slab with different thickness. We choose the doping level  $N = 1.3 \times 10^{18} \text{ cm}^{-3}$ . As is shown in the Fig.1, we can see that there is not much change when the silicon thickness  $D > 0.005\lambda_0$ . The reason is that if  $D > 0.005\lambda_0$ , so  $\exp(-2\sqrt{k_{\parallel}^2 + \epsilon_1 \xi^2 / c^2} D) \ll 1$ . The influence of thickness on this interaction disappears. It can be also

explained with the skin effect of electromagnetic. The skin depth of the material is  $\delta = \sqrt{2/\omega\mu\sigma}$ . When  $D \gg \delta$ , the thickness of material almost doesn't affect the transmission and reflection of electromagnetic field. Therefore, the influence of thickness on this interaction disappears.

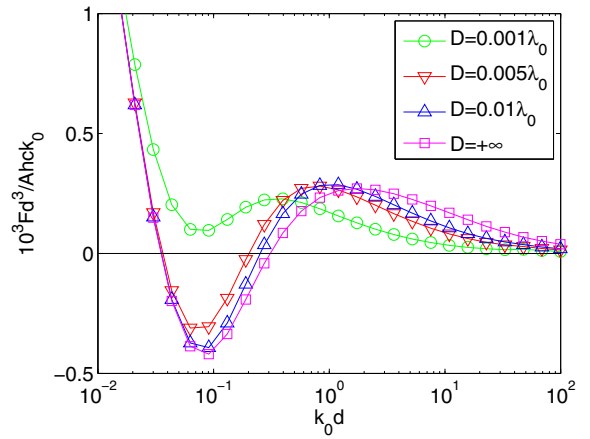


Figure 1 the Casimir interaction between doped silicon slab ( $N = 1.3 \times 10^{18} \text{ cm}^{-3}$ ) and metamaterials ( $f = 10^{-3}$ )

The dependence of the relative force on  $N$  is illustrated in Fig.2 by varying  $D$ . We can see that the doped level has a significant impact on the Casimir effect when  $D < 0.005\lambda_0$ . The higher doping level, the greater the attractive force and the repulsive force is smaller; and the position of the equilibrium point that the Casimir force is zero will be different if the doping level is different. Thereby we can control the strength of the force and the equilibrium point by changing the doping level. When  $D \geq 0.01\lambda_0$ , the doping level almost does not affect the interaction, but the restoring force is significant in the range of  $150 \text{ nm} - 30 \mu\text{m}$ .

The dependence of relative Casimir forces on the filling factor of metamaterials is shown in Fig.3. The filling factor affects the direction of the force. The smaller the filling factor, the greater the repulsive Casimir force. When the filling factor increases, that is, the proportion of metal structure in metamaterials increases, the Casimir interaction is only attractive.

### IV. THE CONCLUSIONS

Based on the Lifshitz theory, we have studied the Casimir forces between doped silicon slab and metamaterials. It is

found that the direction and the magnitude of the force are related to the doping level, the thickness and the filling factor. When the thickness of silicon slab is very small, we can control the position of equilibrium point by changing the

doping level. The smaller the filling factor and the greater the repulsive force; and there exists the restoring force, which may provide a method to deal with the stiction problems.

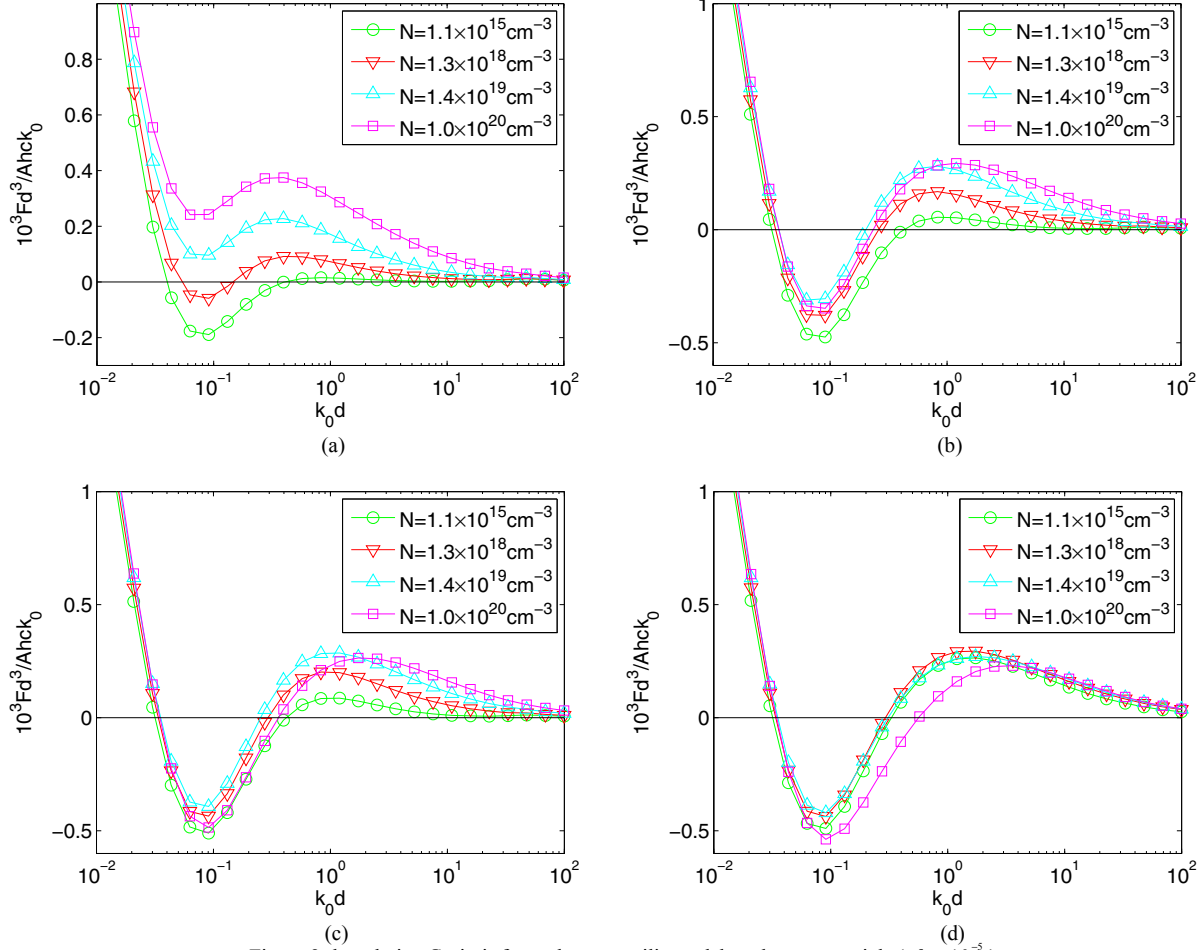


Figure 2 the relative Casimir forces between silicon slab and metamaterials ( $f = 10^{-5}$ )  
(a)  $D = 0.001\lambda_0$ , (b)  $D = 0.005\lambda_0$ , (c)  $D = 0.01\lambda_0$ , (d)  $D = +\infty$

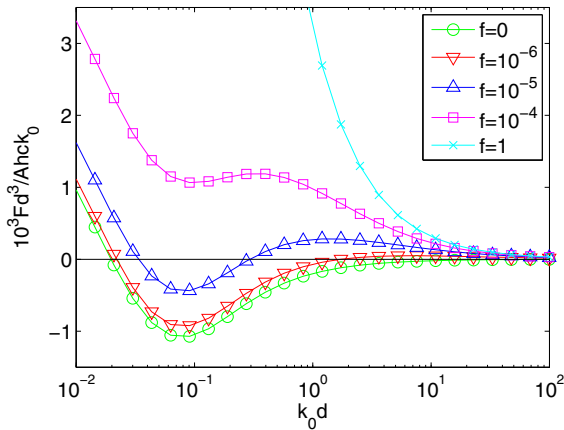


Figure 3 the relative Casimir forces between the doped silicon slab ( $N = 1.3 \times 10^{18} \text{ cm}^{-3}$ ,  $D = 0.1\lambda_0$ ) and metamaterials

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#### REFERENCES

- [1] H. B. G. Casimir, "On the attraction between two perfectly conducting plates," *Proc Kon Ned Akad Wetenschap*, vol. 51, pp. 793-795, 1948.
- [2] G. L. Klimchitskaya, U. Mohideen, V. M. Mostepanenko, "The Casimir force between real materials: Experiment and theory," *Rev. Mod. Phys.*, vol. 81, pp. 1827-1880, 2009.
- [3] Alejandro W. Rodriguez, Federico Capasso, Steven G. Johnson. "The Casimir effect in microstructured geometries," *Nature Photonics*, vol. 5, pp. 211-221, 2011.
- [4] Guo jian-gang, Zhao ya-pu. "Dynamic stability of torsional NEMS actuators with Casimir effect," *Chinese Journal of Sensors and Actuators*, vol. 19, pp.1645-1648, 2006.

- [5] Timothy H. Boyer, "Van der Waals forces and zero-point energy for dielectric and permeable materials," *Phys. Rev. A*, vol. 9, pp. 2078-2084, 1974.
- [6] E.M. Lifshitz, "The theory of molecular attractive forces between solids," *Sov. Phys. JETP*, vol. 2, pp. 73-83, 1956.
- [7] P.J. van Zwol, G. Palasantzas, "Repulsive Casimir force between solid materials with high-refractive-index intervening liquids," *Phys. Rev. A*, vol. 81, 062502, 2010.
- [8] F.S.S. Rosa, D.A.R. Dalvit, P.W. Milonni "Casimir-Lifshitz theory and metamaterials," *Phys. Rev. Lett.*, vol. 100, 183602, 2008.
- [9] R. Zhao, Th. Koschny, E.N. Economou, C.M. Soukoulis, "Repulsive Casimir forces with finite-thickness slabs," *Phys. Rev. B*, vol. 83, 075108, 2011.
- [10] I. Pirozhenko, A. Lambrecht, "Influence of slab thickness on the Casimir force," *Phys. Rev. A*, vol. 77, 013811, 2008.
- [11] Pochi. Yeh, *Optical Waves in Layered Media*, 2<sup>nd</sup> ed., *John Wiley & Sons, Inc. Hoboken, New Jersey*, 2005, pp.83-90.